


Search Notes 	Application/Control No. 10551793	Applicant(s)/Patent Under Reexamination KANEGASAKI ET AL.
	Examiner HEE-YONG KIM	Art Unit 2482

SEARCHED			
Class	Subclass	Date	Examiner
348	79	7/1/2010	H.K

SEARCH NOTES		
Search Notes	Date	Examiner
microscope and (mirror with target)	6/29/2010	H.K
microscope and (mirror with target) and (vertical\$2 light)	6/29	H.K
microscope and (aperture with wavelength with distance)	6/29	H.K
microscope and ((numerical aperture) near2 (light and lens))	6/29	H.K
reflect\$3 with (coat\$3 or bond\$3 or superimpos\$3)	6/30	H.K
((reflect\$4 (layer or plane) with (bond\$3)) with (target or sample)	6/30	H.K
focal depth with distance with reflect\$3 (plane or surface)	7/1	H.K
field parameter with numerical aperture	7/1	H.K
NPL search (focal depth and wavelength and numerical aperture)	7/1	H.K
Inventor Search at Edan	7/1	H.K
Discussed with Andy Rao about Allowability (Andy agrees on allowability)	2/8/2011	H.K

INTERFERENCE SEARCH			
Class	Subclass	Date	Examiner
348	79	2/9/2011	H.K

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